

ICS 29.045  
CCS H 21

**YS**

**NONFERROUS METALS INDUSTRY STANDARD OF THE  
PEOPLE'S REPUBLIC OF CHINA**

**YS/T 23-2016**

Replacing YS/T 23-1992

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**Test method for thickness of epitaxial layers - Stacking fault  
size**

硅外延层厚度测定 堆垛层错尺寸法

**(English Translation)**

**Issued on: April 5, 2016**

**Implemented on: September 1, 2016**

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**Issued by: Ministry of Industry and Information Technology**

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### What this standard covers

This standard specifies methods for measuring the thickness of silicon epitaxial layers using the stacking fault size method.

### Document data

International classification (ICS): 29.045.

Chinese classification (CCS): H21.

Estimated length of the Chinese original: 7,745 words.

Supersedes the earlier edition YS/T 23-1992.